



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Yoko IKEDA et al.

Serial No.:

09/452,149

Filed:

1 December 1999

For:

INSPECTING METHOD, INSPECTING SYSTEM, AND

METHOD FOR MANUFACTURING ELECTRONIC DEVICES

Art Unit:

2623

RECEIVED

Examiner:

Virginia M. KIBLER

JUN 3 0 2003

**AMENDMENT** 

Technology Center 2600

Honorable Commissioner for Patents Washington, D.C. 20231

27 June 2003

Sir:

In response to the Office Action mailed 27 March 2003 in connection with the above-identified application, Applicant respectfully submits the following amendments and remarks.